

H-811

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

N. KOFUJI et al

Serial No. 09/363,191

Group Art Unit: 1763

Filed: July 29, 1999

Examiner: L. Alejandro Mulero

For: DRY ETCHING APPARATUS AND A METHOD OF  
MANUFACTURING A SEMICONDUCTOR DEVICEPRELIMINARY AMENDMENTCommissioner of Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated December 21, 2001,  
please amend the above-identified application as follows. A  
Continued Prosecution Application (CPA) Request is being filed  
concurrently herewith by Applicants.

IN THE CLAIMS

Cancel claims 5 and 10-33 without prejudice or  
disclaimer; amend claim 1; and add new claims 34-36 as  
follows:

1. (Twice Amended) A dry etching apparatus for treating  
a body comprising:
- a chamber;
  - a holder in said chamber to receive a body to be treated;
  - means for introducing gas into said chamber;